5/19/99

S/N 09/135.413

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Leonard Forbes et al.

Serial No.:

09/135,413

Filed: Title:

August 14, 1998

DEAPROM HAVING AMORPHOUS SILICON CARBIDE GATE

INSULATOR

AMENDMENT AND RESPONSE

sistant Commissioner for Patents CETH Washington, D.C. 20231

Tle = A19/97

1d the above
6275668 In response to the Office Action mailed February 23, 1999, please amend the above identified patent application as follows:

IN THE TITLE

Please delete the title and replace it with the following: --Method For Operating A DEAPROM Having An Amorphous Silicon Carbide Gate Insulator--.

IN THE SPECIFICATION

Please amend the specification by deleting lines 5-18 on page 1 of the originally filed application, beginning with the heading "Cross Reference To Related Applications."

On page 19, lines 26-27, please replace "serial number "with --serial number

08/903,453--.

MAY 2 5 1000

IN THE CLAIMS

Please cancel claims 25-27 and 39-42.

TECHNOLOGY CENTER 2800

PATENT

Examiner: Viet O. Nguyen

Group Art Unit: 2818 Docket: 303.354US2

Please amend the claims as follows:

(Amended) A method of using a floating gate transistor having a floating gate electrode

and an adjacent amorphous silicon carbide (a-SiC) gate insulator between the floating gate electrode and a substrate, the method comprising:

storing data by changing [the] a charge of the floating gate electrode; reading data by detecting a current between a source and a drain in the substrate; and